U.S. PATENT DOCUMENTS

5,369,280 A * 11/1994 Liddiard ..... 250/370.08
5,589,689 A * 12/1996 Koskinen ..... 250/339.01
5,602,393 A * 2/1997 Gerard ..... 250/338.4
5,647,946 A * 7/1997 Belcher et al. ..... 156/345
5,760,398 A * 6/1998 Blackwell et al. ..... 250/332
RE35,872 E * 8/1998 Fenner et al. ..... 250/336.2
5,801,070 A * 9/1998 Zanini-Fisher et al. ..... 438/54
5,804,462 A * 9/1998 Liu et al. ..... 438/53
5,813,764 A * 9/1998 Visser et al. ..... 374/12
5,965,886 A * 10/1999 Sauer et al. ..... 250/332
6,034,374 A * 3/2000 Kimura et al. ..... 250/370.08
6,079,873 A * 6/2000 Cavicchi et al. ..... 374/10
6,194,722 B1 * 2/2001 Fiorini et al. ..... 250/338.1
6,198,098 B1 * 3/2001 Laou ..... 250/338.1
6,239,431 B1 * 5/2001 Hilton et al. ..... 250/336.2
6,300,632 B1 * 10/2001 Liu et al. ..... 250/338.4
6,305,840 B1 * 10/2001 Kim et al. ..... 374/133
6,339,220 B1 * 1/2002 Oda ..... 250/338.1
2002/0040967 A1 * 4/2002 Oda ..... 250/228.1

OTHER PUBLICATIONS

M Kimura and K Komatsuzaki: "Microheater Made of Heavily Boron Doped Single Crystal Silicon Beam" Technical Digest of the Sensor Symposium, XX, XX, 1992, pp. 169–172, XP002159427.

Chou B C S et al: "Micromachining on (111)–oriented silicon" Sensors and Actuators A, CH, Elsevier Sequoia S.A., Lausanne, vol. 75, No. 3, Jun. 8, 1999, pp. 271–277, XP004175049 ISSN: 0924–4247.

* cited by examiner